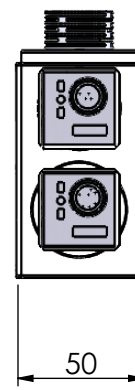
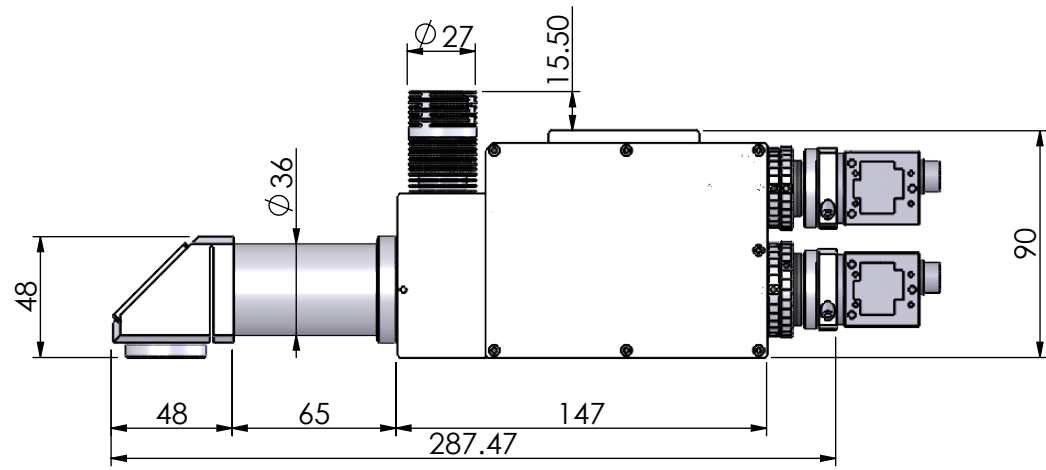
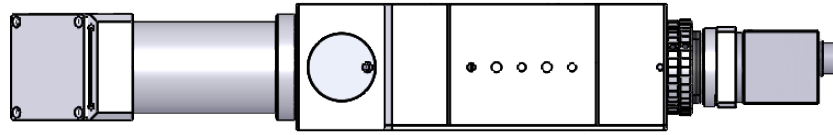


REV. NO	REVISION NOTE	DATE	SIGNATURE	CHECKED
△				



본 도면은 리스광시스템(주)의 자산이므로 허가없이 복제 및 외부 반출을 금함.
 This drawing and ideas are protected by LEES Optical System, Inc.

4	OPTICAL MAGNIFICATION	WD(mm)	DEPTH OF FIELD	RESOLUTION	NA	PARAXIAL WORKING F/#	F.O.V	MOUNT	SCALE	ANGLE	DESIGNED BY	CHECKED BY	APPROVED BY	TITLE
	0.5X	160	±0.88mm	7.45um	0.045	5.6	H6.4 xV4.8(1/2"), H4.8 x V3.6(1/3")	C-MOUNT	1:3					DUAL MAGNIFICATION
	2.5X		±0.17mm			27.8	H2.13 xV1.6(1/2"), H1.6 x V1.2(1/3")		MM	INCH				LP11025-R02-M00
										DWG. NO	LP11025-R02-M00			